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JC14 Rec'd PCT/PTO 06 MAY 2005

Date of Deposit: May 6, 2005

Case No. 9905/25

UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
 ASPAR et al.)
 Serial No.: Not Yet Assigned) Examiner:
 Filing Date: Herewith) Not Yet Assigned
 For: METHOD FOR FORMING) Group Art Unit:
 A BRITTLE ZONE IN A SUBSTRATE) Not Yet Assigned
 BY CO-IMPLANTATION)

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
 P.O. Box 1450
 Alexandria, Virginia 22313-1450

Dear Sir:

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98, and more particularly in accordance with 37 C.F.R. §1.97(b), Applicants hereby cite the following references:

No.	Date of Publication	Patentee/Applicant/Assignee
US 6,150,239	11/21/2000	Goesele et al.
US 6,020,252	02/01/2000	Aspar et al.
US 5,374,564	12/20/1994	Bruel
FR 2 774 510 A1	08/06/1999	France
FR 2 773 261 A1	07/02/1999	France
FR 2 767 416 A1	02/19/1999	France
FR 2 748 851 A1	11/21/1997	France
FR 2 748 850 A1	11/21/1997	France
FR 2 681 472 A1	03/19/1993	France
WO 00/63965	10/26/2000	PCT
WO 99/39378	08/05/1999	PCT
EP 0786801 A1	07/30/1997	EPO
EP 0801419 A1	10/15/1997	EPO
11-87668	03/30/1999	Japan

Agarwal et al., *Efficient Production of Silicon-on-Insulator Films by Co-Implantation of He+ with H+*, 1998 American Institute of Physics, Volume 72, number 9, March 2, 1998, pp. 1086-1088.

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For the Examiner's convenience, Applicants are enclosing Form PTO-1449 (one sheet), and as each of the listed references is in English, no further commentary is believed to be necessary, 37 C.F.R. §1.98(a)(3). Applicant respectfully requests the Examiner's consideration of the above references and entry thereof into the record of this application.

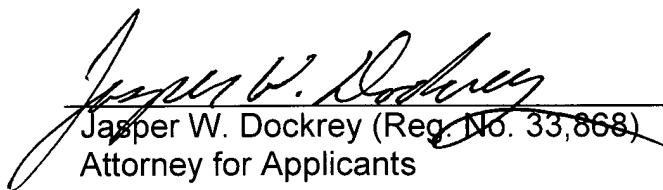
Also enclosed is a copy of the International Search Report issued on March 19, 2004 for corresponding PCT Application No. PCT/FR03/03256 of the above-identified application.

By submitting this Statement, Applicants are attempting to fully comply with the duty of candor and good faith mandated by 37 C.F.R. §1.56. As such, this Statement is not intended to constitute an admission that any of the enclosed references, or other information referred to therein, constitutes "prior art" or is otherwise "material to patentability," as that phrase is defined in 37 C.F.R. §1.56(a).

Applicants have calculated no fee to be due in connection with the filing of this Statement. However, the Director is authorized to charge any fee deficiency associated with the filing of this Statement to a deposit account, as authorized in the Transmittal accompanying this Statement.

Respectfully submitted,

May 6, 2005



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10/534199

FORM PTO-1449	SERIAL NO. Not Yet Assigned	CASE NO. 9905/25 (BIF023239/DM)
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE Herewith	GROUP ART UNIT Not Yet Assigned
	APPLICANTS: ASPAR et al.	

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER Number-Kind Code (if known)	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
A1	6,150,239	11/21/2000	Goesele et al.		
A2	6,020,252	02/01/2000	Aspar et al.		
A3	5,374,564	12/20/1994	Bruel		

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER Number-Kind Code (if known)	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
A4	FR 2 774 510 A1	08/06/1999	France		
A5	FR 2 773 261 A1	07/02/1999	France		
A6	FR 2 767 416 A1	02/19/1999	France		
A7	FR 2 748 851 A1	11/21/1997	France		
A8	FR 2 748 850 A1	11/21/1997	France		
A9	FR 2 681 472 A1	03/19/1993	France		
A10	WO 00/63965	10/26/2000	PCT		
A11	WO 99/39378	08/05/1999	PCT		
A12	EP 0786801 A1	07/30/1997	EPO		
A13	EP 0801419 A1	10/15/1997	EPO		
A14	11-87668	03/30/1999	Japan		Abstract

EXAMINER INITIAL	OTHER ART - NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.)	
A15	Agarwal et al., <i>Efficient Production of Silicon-on-Insulator Films by Co-Implantation of He+ with H+</i> , 1998 American Institute of Physics, Volume 72, number 9, March 2, 1998, pp. 1086-1088.	

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.